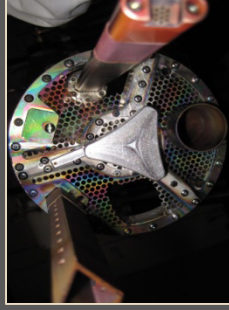
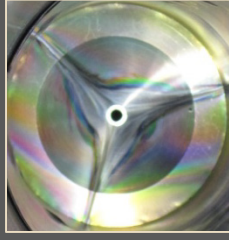
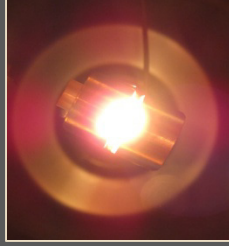
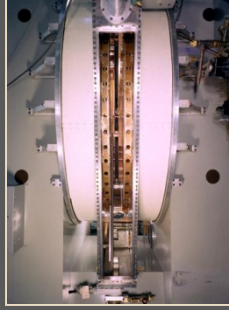


CURRENT DEVELOPMENTS OF THE VENUS ION SOURCE IN RESEARCH AND OPERATIONS



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Sep 27, 2012

ECRIS 2012

Outline

I. Quick overview of VENUS

II. Sputter probe test results

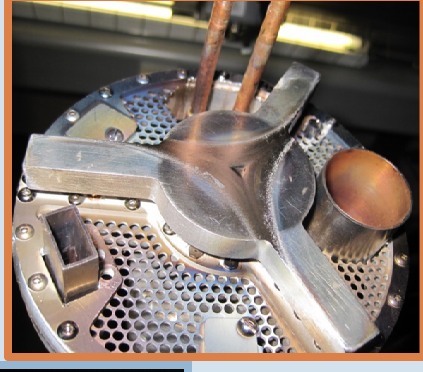
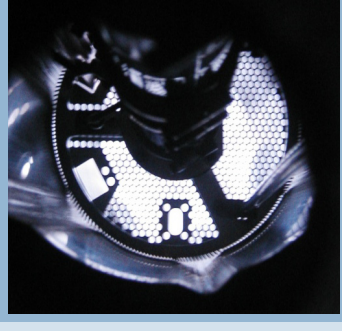
III. LoT Oven:

I. Bi^{56+} for cocktails

II. Liner test & Calcium consumption

IV. High Voltage Upgrade & Helium Results

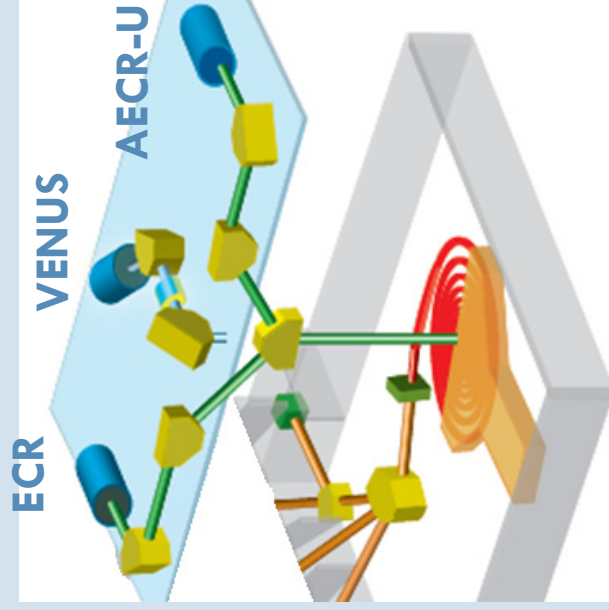
V. Plasma chamber



VENUS Layout on Vault Roof

VENUS Mission:

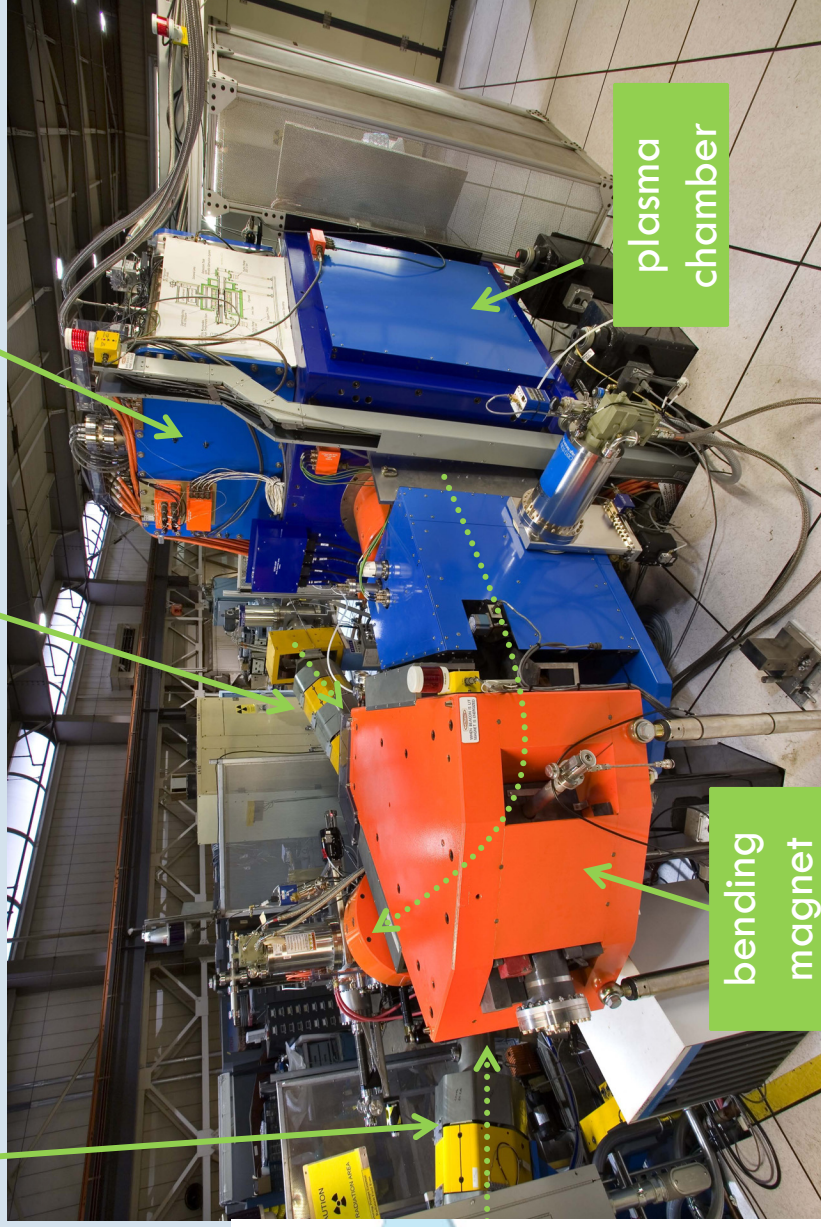
1. Prototype for FRIB
2. Research tool
3. Injector for the 88" cyclotron



AECR
beamline

ECR
beamline

cryostat



bending
magnet

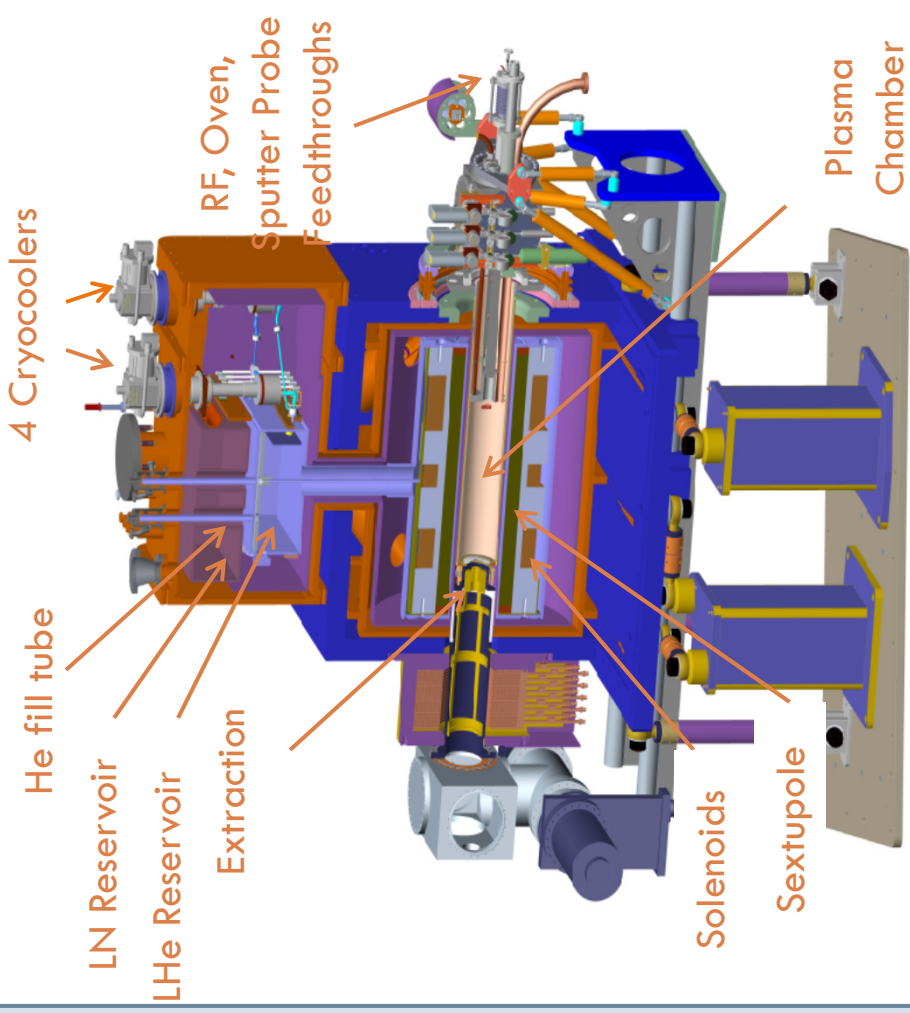
plasma
chamber

Overview of VENUS

- **Fully superconducting**, Niobium-Titanium sextupole & 3 solenoids enclosed in LHe
- **LN Reservoir**: 70K, dissipates heat from normal conducting leads
- **LHe Reservoir**: 4.2K
- **Four two stage cryocoolers** which provide **6W total cooling power at 4.2K**, recondense evaporated He, 1st stage (45K) cools part of the Cu leads

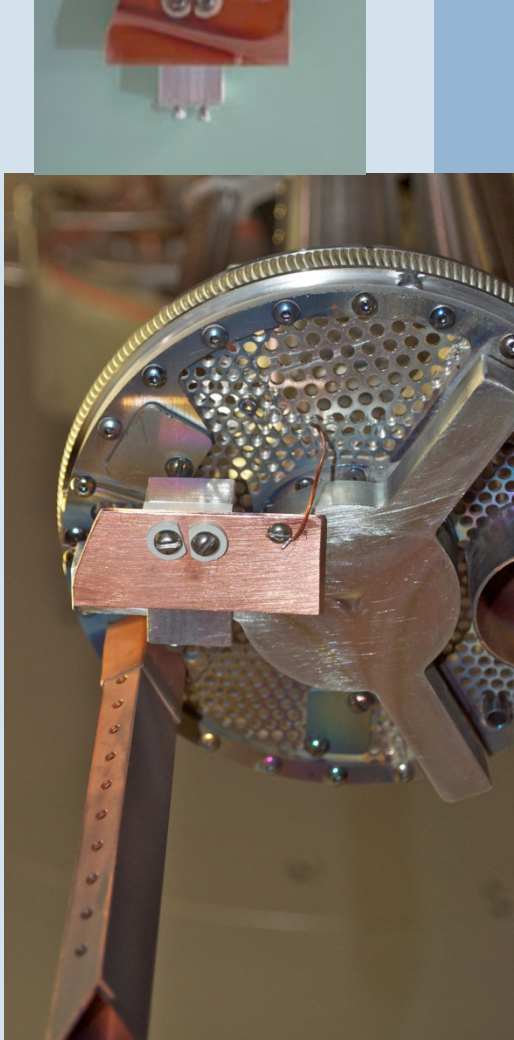
• **Recently ran 22 months straight**

Maximum Injection Field, on axis	4.0T
Maximum Extraction Field, on axis	3.0T
Maximum Radial Field, at wall	2.2T
Chamber Diameter	14cm
Chamber Length	50cm
18 GHz Maximum Power	2kW
28 GHz Maximum Power	10kW
28 GHz Maximum Power Injected	6.5kW
18+28 GHz Maximum Power Injected	8.5kW



Sputter Probe Development

- ❑ For use in cocktails to provide V, Ag, Ta, Cu, and possibly others....
- ❑ Cocktail: Mixture of ions of similar M/Q delivered to cyclotron from ECR simultaneously
- ❑ Direct ion sputtering technique
- ❑ Plasma ions accelerated toward sample impact surface and sputter material into plasma
- ❑ Capability will make VENUS a good backup for A cocktail

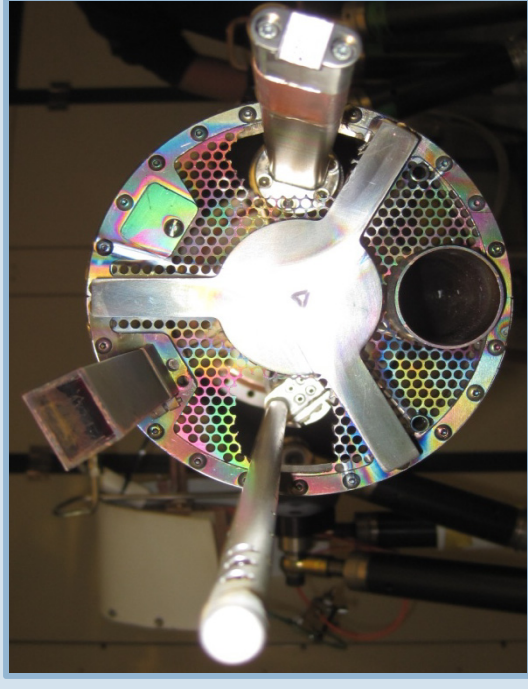
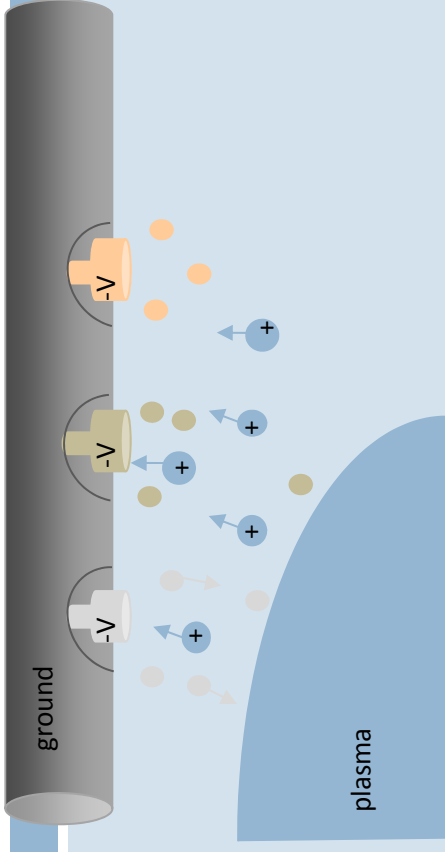


10MeV/u	M/Q	Production Method	LET (MeV/(mg/cm ²))	RANG E (μm)
¹¹ B ³⁺	3.67	MIVOC CHAMBER	0.89	305.7
¹⁸ O ⁵⁺	3.60	GAS	2.19	226.4
²² Ne ⁶⁺	3.67	GAS	3.49	174.6
²⁹ Si ⁸⁺	3.63	GAS	6.09	141.7
⁴⁰ Ar ¹¹⁺	3.64	GAS	9.74	130.1
⁵¹ V ¹⁴⁺	3.64	Sputter Probe	14.6	113.4
⁶⁵ Cu ¹⁸⁺	3.61	Sputter Probe	21.2	108
⁸⁴ Kr ²⁴⁺	3.5	GAS	30.2	113.1
⁸⁹ Y ²⁵⁺	3.56	Sputter Probe	34.7	102.2
¹⁰⁷ Ag ²⁹⁺	3.69	Sputter Probe	48.2	90.0
¹²⁴ Xe ³⁴⁺	3.65	GAS	58.8	90.0

easily removed and impractical

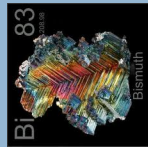
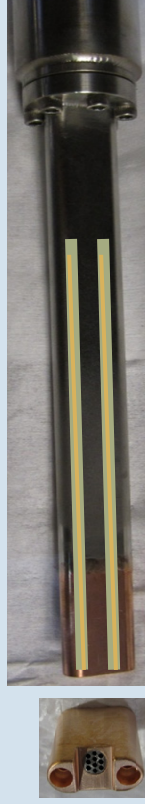
Sputter Probe Development

- Water-cooled support tube, moveable bellows, 3 sample capability
- Initial tests positive
- Soon learned position of probe not ideal: inserted at flute position
- Radial position is 5.6cm, chamber radius is 7.2cm



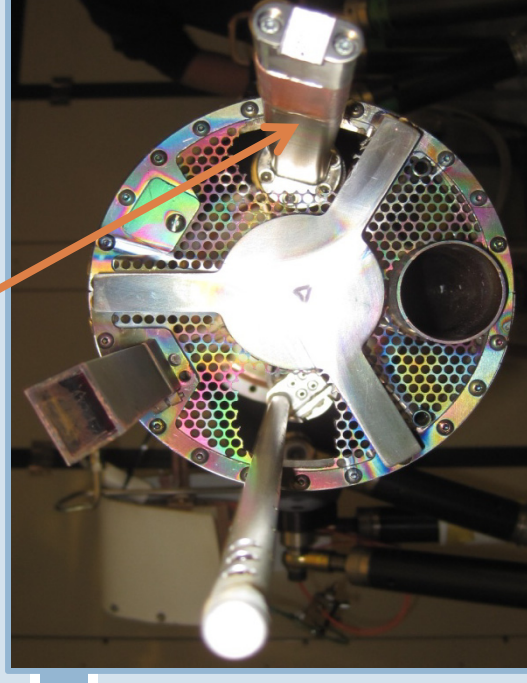
Oven Development: Low Temp

- Completed July, 2011
- Operates up to 650°C to vaporize metals
- Expands VENUS' metal production capability



Bismuth Development: 10MeV Cocktail

- Accelerated $^{209}\text{Bi}^{56+}$, Bi^{57+} , Bi^{58+} through cyclotron
- At cyclotron extraction had 0.08eA of Bi^{56+}
- Increases maximum Liner Energy Transfer in Silicon by 35% for our 10MeV Cocktail



Calcium Development: High Intensity

- avg current of 100eμA of $^{40}\text{Ca}^{11+}$
- Used 63mg, consumption rate of 0.67mg/hr
- 2% efficiency into $^{40}\text{Ca}^{11+}$, ~9% total efficiency
- Good news for high intensity ^{48}Ca runs where 1mg of ^{48}Ca ~\$250 (63mg ~\$15,750)
- Good efficiency = No liner required = No interruption to cocktail runs



Oven Development: Low Temp + Liner

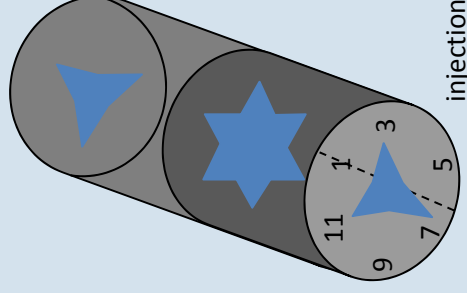
- Tantalum liner test 03/2012 in attempt to increase efficiency for ^{48}Ca beams
- 3 layers of 0.003" thick Ta, 12" long
- Used only 18GHz heating at 18GHz sextupole/solenoid fields

Pros:

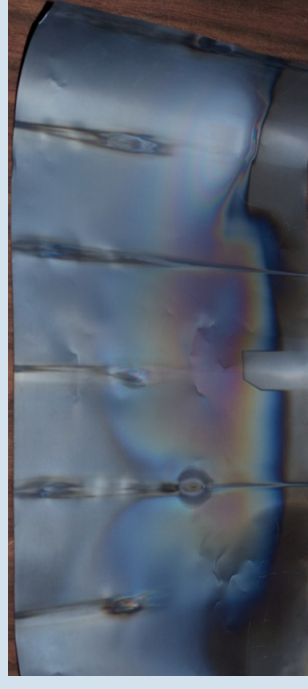
- $\emptyset$

Cons:

- Needed to raise sextupole field to 28GHz field (460A, 2.2T) in order to reduce Ta peaks in spectra
- Did not increase efficiency.
No liner: 0.67mg/hr
With liner: 0.73mg/hr

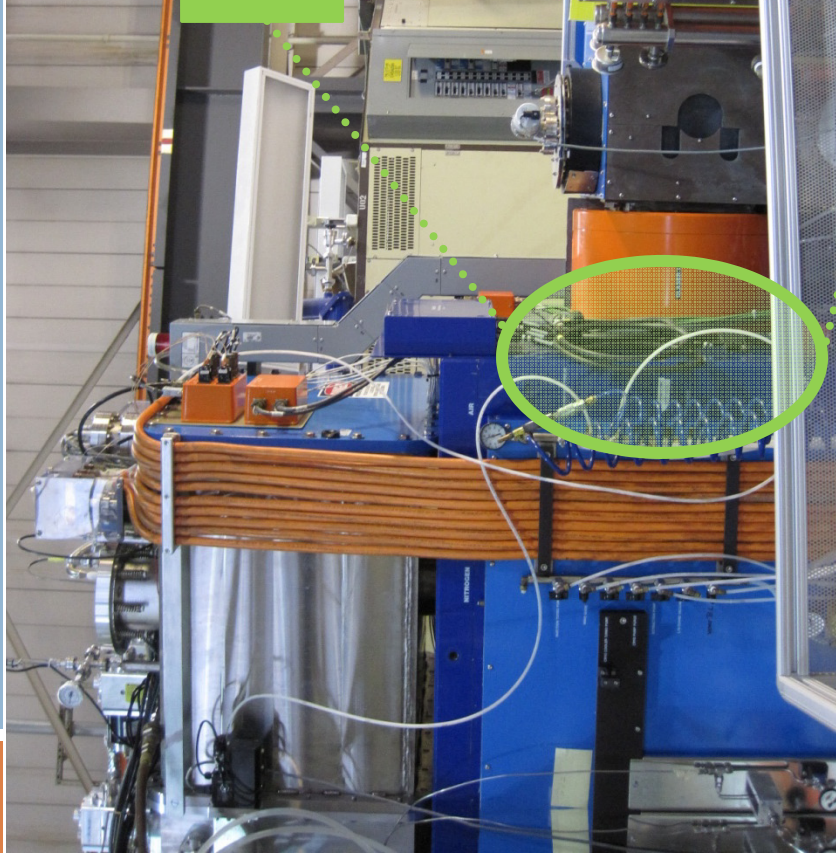


extraction No white CaO residue formed on liner!



5 3 1 11 9 7

High Voltage Upgrade



beam
extraction
hole

@ HV

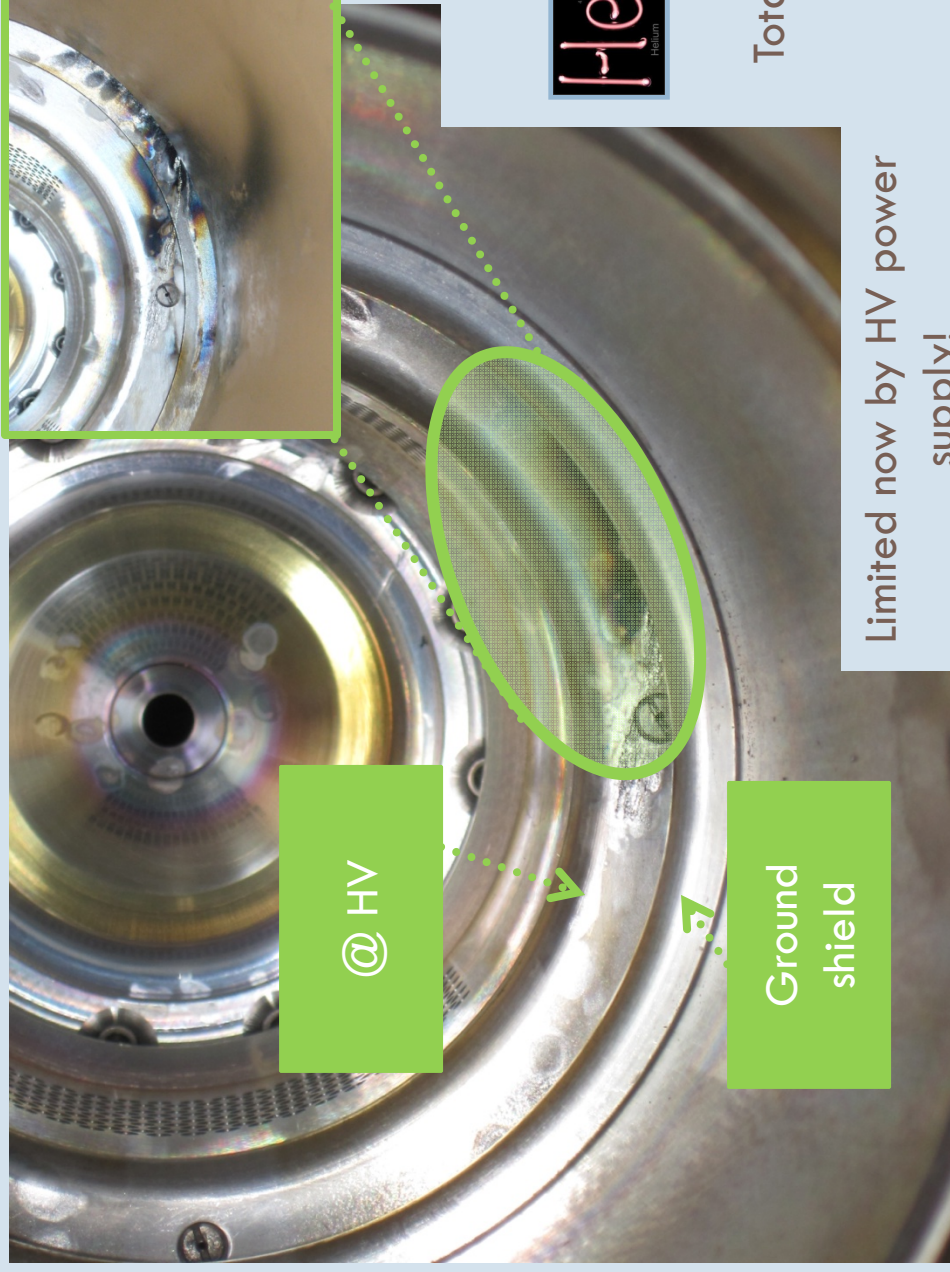
Ground
shield

plasma

Puller
(0 to -10kV)

- Source would not hold voltage above 22kV

High Voltage Upgrade



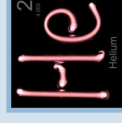
Limited now by HV power supply!



New Record Achieved:

${}^4\text{He}^{1+}$: 9.3emA

${}^4\text{He}^{2+}$: 11emA



Source Parameters:

Total Extracted: 25emA @ 25kV

Inj. Pressure: 1×10^{-6} mbar

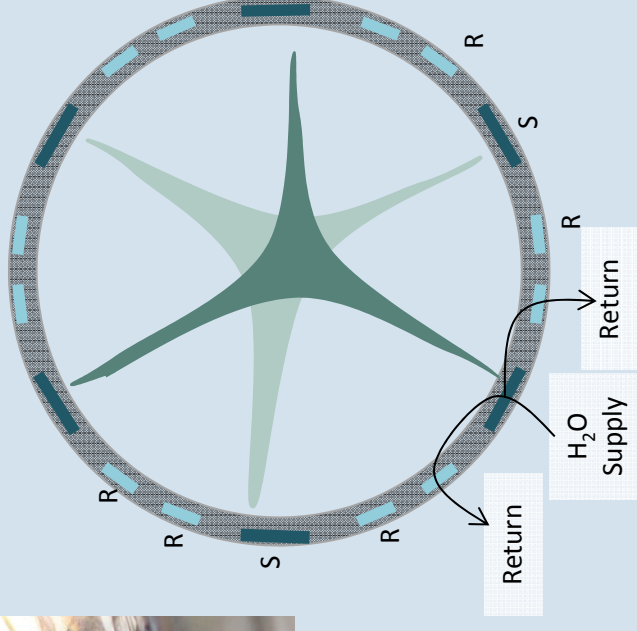
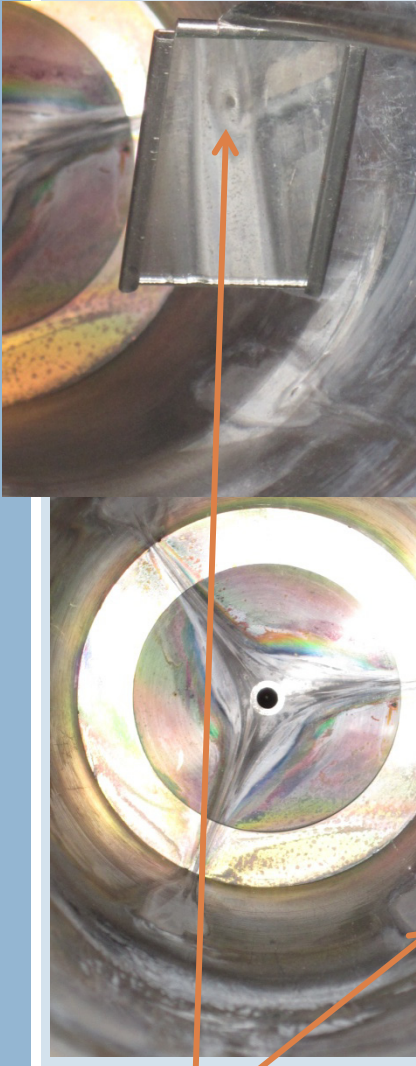
18GHz: 1745W

28GHz: 1000W

Bias Disk: - 335V, 58mA

VENUS Plasma Chamber

- Burned a hole in plasma chamber at 7 o'clock position injection flute
- Measured a wall thickness of 0.053" at thinnest location
- Same location as 2005's 28GHz Gyrotron accident. This hole attributed to more continuous operation
- Important to consider for VENUS II and 4th generation



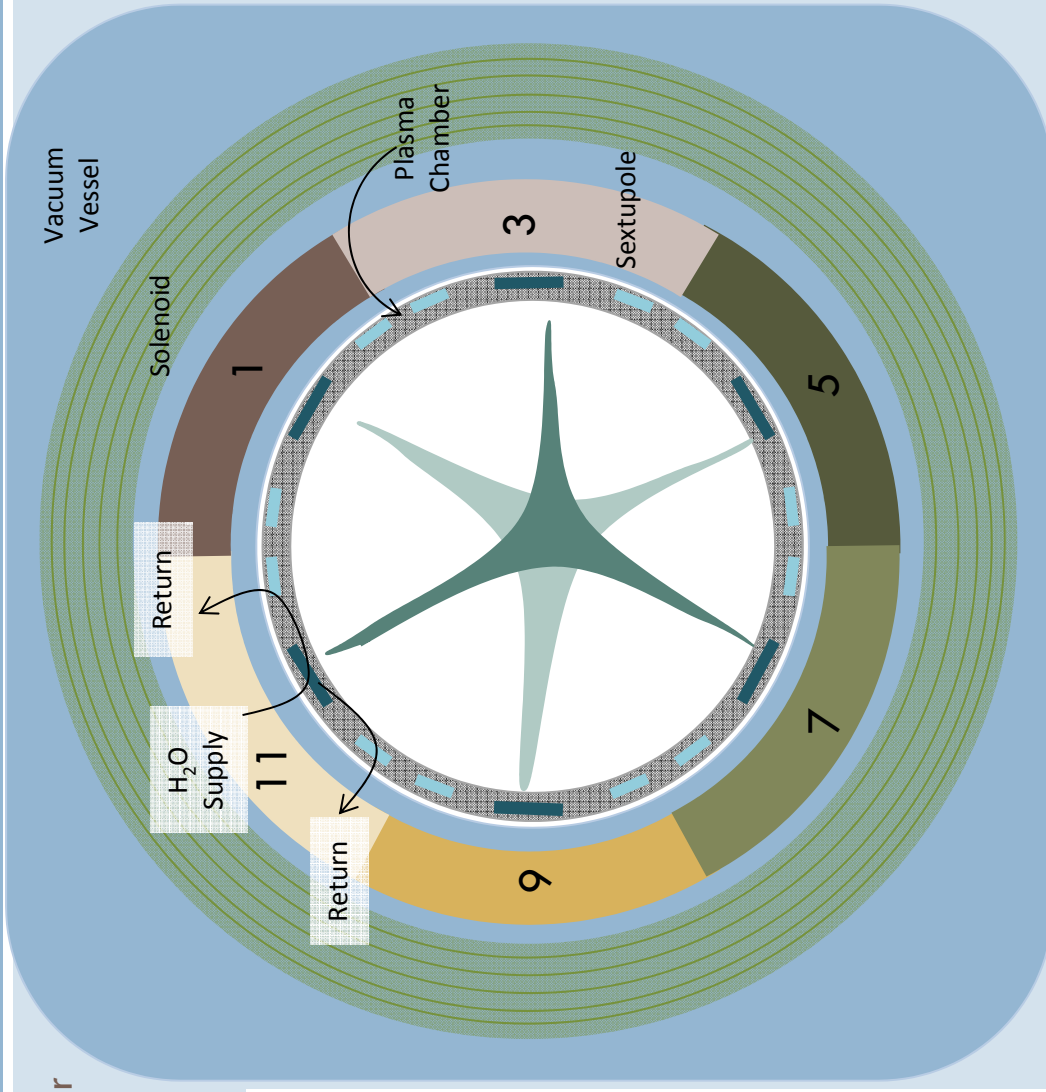
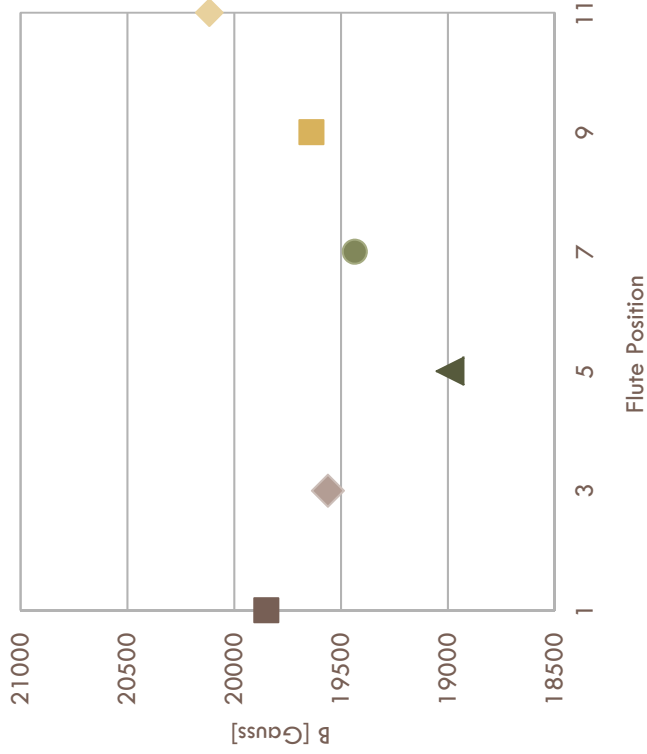
VENUS Plasma Chamber



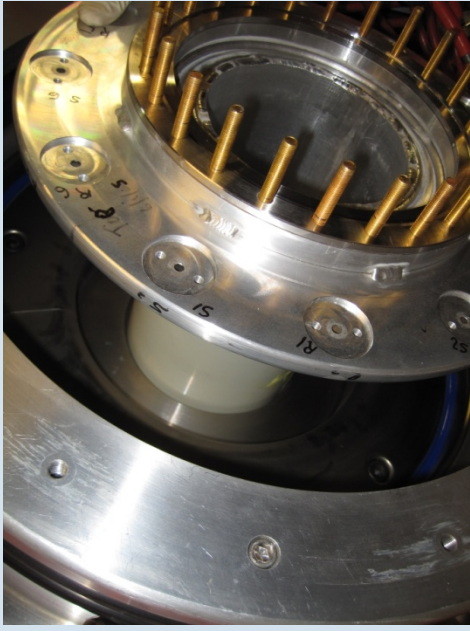
- Investigation of the alignment of chamber to sextupole magnets revealed that chamber sits high by 1 mm (40mils)

VENUS Sextupole Field at the Wall at Hole

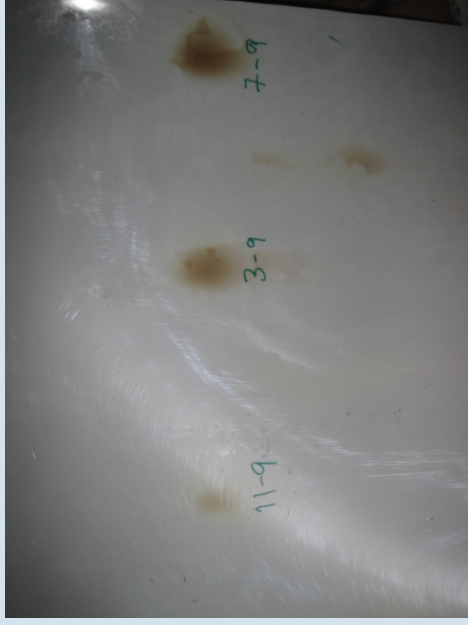
Location
 $I=460A$



VENUS Plasma Chamber



- Inspection of the mylar insulation reveals damage at position of the 3 injection flutes
- High energy x-rays going through 2mm Ta sheet
- 9 layers of 0.015" mylar sheet
- Reduced to 6 layers in attempt to correct alignment offset of 1mm



Summary

- VENUS satisfied most FRIB requirements
- Continue to make advances in beam intensities: He, U (G. Machicoane's talk)
- LoT oven has succeeded in producing beams for 88" researchers
- Sputter Probe still in development
- VENUS usage in operations increased from 1.1% in 2007 to 17.5% in 2012 (~850hrs)
- We continue to learn and work towards improvements!

Thank you!



ECR Group: (left to right) J. Benitez, Claude Lyneis, Markus Strohmeier, Ken Franzen

FRIB ECR Requirements			
Element		I (eμA)	VENUS(eμA)
Argon	⁴⁰ Ar ⁸⁺	378	525 of 8+
Calcium	⁴⁸ Ca ¹¹⁺	468	400 of ⁴⁰ Ca ¹¹⁺
Xenon	¹²⁴ Xe ¹⁸⁺	334	432 of 26+
Bismuth	²⁰⁹ Bi ²⁹⁺	422	300 of 31+
Uranium	²³⁸ U ^{33,34+}	440	840

